



Initial Review  
**BOX AF**

730-117

AF 1107

THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

Hidehiko KIRA et al.

Serial Number: 08/393,677

Filed: February 24, 1995

For: METHOD AND APPARATUS FOR FABRICATING SEMICONDUCTOR DEVICE

RECEIVED

JUN 13 1997

GROUP 1100

Group Art Unit: 1107

Examiner: David E. GRAYBILL

16 B  
6-16-97  
U. Ross  
NE/C  
#20 mR  
12/11/97

**RESPONSE UNDER 37 CFR §1.116**  
**- EXPEDITED RESPONSE -**  
**GROUP ART UNIT 1107**

*DO NOT ENTER*  
*6-17-97*  
**BOX AF**

Assistant Commissioner for Patents  
Washington, D.C. 20231

May 30, 1997

Sir:

In response to the Office Action dated December 4, 1996, please amend the above-identified application as follows:

**IN THE CLAIMS:**

Amend claim 1 as follows:

1. (Twice Amended) A fabrication method of a semiconductor device comprising

*C*  
the steps of:

12/1997 RJHNSON 00000671 08393677 930.00 OP  
C:117